

Applicant: M. Kawaguchi
U.S.S.N.: 09/470,615
RESPONSE TO OFFICE ACTION
Page 2

Please amend the subject application as follows:

IN THE CLAIMS

Amend claims 1 and 2 to read as follows:

1. (AMENDED) A mechanism for supporting a substrate to be coated with the film, which mechanism is used in a film forming apparatus, comprising:
a stage for receiving a substrate which has been transported into the film forming apparatus to form a film on the substrate;
a shaft member for angularly displacing the stage, that is bearing the substrate, from a substrate receiving position at which the stage received the substrate, to a film forming position at which a substrate bearing surface of the stage is vertical or substantially vertical;
a plurality of support members which are provided so as to protrude from the substrate bearing surface of the stage, for supporting an end surface of the substrate, which faces downwards, when the stage is angularly displaced to the film forming position; and
moving means for moving the support members.

2. (AMENDED) A mechanism for supporting a substrate to be coated with the film, which mechanism is used in a film forming apparatus, comprising:
a stage for receiving a substrate which has been transported into the film forming apparatus to form a film on the substrate;
a shaft member for angularly displacing the stage, that is bearing the substrate, from a substrate receiving position at which the stage received the substrate, to a film

Applicant: M. Kawaguchi
U.S.S.N.: 09/470,615
RESPONSE TO OFFICE ACTION
Page 3

forming position at which a substrate bearing surface of the stage is vertical or substantially vertical;

Ar end
a plurality of support members which are provided so as to protrude from the substrate bearing surface of the stage, for supporting an end surface of the substrate, which faces downwards, when the stage is angularly displaced to the film forming position;

g/g
moving means for moving the support members; and
wherein the moving means causes the support members to move in parallel in one direction of three dimensional directions on the stage or causes the support members to rotationally move on the stage.

[Add] new claim(s) 13-16 that read as follows:

Xo
13. (ADDED) The mechanism for supporting a substrate to be coated with the film of claim 1, wherein the moving means is configured and arranged so as to cause the support members to move in one direction with respect to a long axis of the support members.

Xo
14. (ADDED) The mechanism for supporting a substrate to be coated with the film of claim 1, wherein the moving means is configured and arranged so as to cause the support members to move in a direction generally perpendicular to a long axis of the support members.